

#### Large Angle Beamstrahlung Monitor (LABM) @ SuperB with Si-CNT detector

M. Ambrosio, C. Aramo, G. Bonvicini, M. Masullo and E. Nappi



# The LABM provides a set of direct and passive measurements

It is well known that the major technical challenge of the future Super B factories is to produce and maintain colliding beams of a size never achieved before.

Whereas current e+e- storage rings produce beams with transverse heights y 3 µm and widths x 350 µm, the new factories nominal parameters are 50 nm and 10 µm respectively.

Even at the relatively large sizes of today's beams, transverse mismatches reduce and ultimately limit the machine's luminosity.

The LABM measures the beamstrahlung light emitted at large angle (large compared to the typical  $1/\gamma$  angle of radiation produced by ultra relativistic beams), and relates it to beam parameters so that the beam-beam collision can be optimized for luminosity.



#### **Ground motion: LABM vs luminosity monitor**

- A luminosity monitor does not pick out higher corrections. If luminosity decreases due to defocussing, and luminosity feedback is activated, the luminosity will decrease further
- Even if the motion is purely offset-y, a luminosity monitor will not specify whether the correction is up or down
- LABM can produce an asymmetry, A<sub>u-d</sub>=(R<sub>u</sub>-R<sub>d</sub>)/(R<sub>u</sub>+R<sub>d</sub>), which will specify the direction of deflection. For offset-y=1nm, θ=7.5mrad, and the UV PMTs, A<sub>u-d</sub>=0.01-0.02, recorded on two sides and two polarizations



#### Large angle beamstrahlung power

At the future B factories, beamstrahlung is abundantly produced (5.4 and 1.3 kW total radiated power for the SuperKEKB HER and LER respectively), and small (2 × 2.8 mm<sup>2</sup>) 45 degrees mirrors placed inside the Beam Pipe at 7 and 8 mrad and located at ±90 degrees in azimuth will intercept of the order of  $10^{12}$  beamstrahlung visible photons per second at nominal conditions.

Such abundant signal will provide a lot of opportunity to precisely measure beam parameters.

$$\frac{d^2 I}{d\Omega d\omega} = \frac{3\sigma_z}{4c\pi\sqrt{\pi}} P_0 \frac{1}{\gamma^4 \theta^4} \exp(\frac{-\omega^2 \theta^4 \sigma_z^2}{16c^2})$$

## **Optics Box – Grating mirrors**

Mirrors =  $1 \text{ cm}^2$ 

UV Intensity = 10<sup>12</sup> photons/sec

Detector: High UV photoresponsivity large are uniformity The monitor consists of four viewports, located at the top and bottom of the beam pipe.

Each viewport is a 2 X 2.8 mm<sup>2</sup> primary mirror, reflecting light out of the beam pipe. Light is transported through an optical channel to an optical box (one box serves each side, or two viewports per box), where it is separated into two transverse polarizations and four different wavelength bands, totaling 32 optical and electronic channels.

# **Light Collector and grating**

The light is split into two polarizations by a wide band Wollaston prism, and each polarization is spread onto four counters by a ruled grating, which maximizes the reflected intensity in the first order peak. By changing just the grating and the photodetectors, this device can monitor the intervals 225 < $\lambda$ < 495 nm (UV), 300 < $\lambda$ < 660 nm (VIS), and 400 < $\lambda$ < 880 nm (IR). The individual light beams are concentrated by light collectors so that both large photon counters (PMTs) and Si-PMTs can be used.





LFF Workshop – Napoli – November 22-23, 2012

### Photodetector to be used

For an efficient reconstruction of beam light intensity and frequency, the ideal detector has to be one with high efficiency in all the wavelenght range 225 – 880 nm. It is not necessary to detect single photon, due to the high beam intensity. The ideal would be a photodetector with a quite uniform efficiency in all the range.





#### **SEM Images**

![](_page_8_Picture_1.jpeg)

![](_page_8_Picture_2.jpeg)

![](_page_8_Picture_3.jpeg)

![](_page_8_Picture_4.jpeg)

![](_page_8_Picture_5.jpeg)

![](_page_8_Picture_6.jpeg)

![](_page_8_Picture_7.jpeg)

![](_page_8_Picture_8.jpeg)

Carla Aramo – INFN Napoli

LFF Workshop – Napoli – November 22-23, 2012

![](_page_9_Picture_0.jpeg)

9.0 nm

23.5 nm

18.5 nm

8.4 nm

![](_page_9_Picture_1.jpeg)

- External diameter: 15 25 nm
- Internal diameter: 5 10 nm
- Average number of nanotubes: 10 15

#### **CNT Characteristics**

![](_page_9_Figure_6.jpeg)

![](_page_9_Picture_7.jpeg)

#### Growth Mechanism of Carbon Nanotubes (CVD and PECVD)

![](_page_10_Figure_1.jpeg)

![](_page_10_Picture_2.jpeg)

catalyst

![](_page_10_Picture_3.jpeg)

# **Silicon-CNT radiation detector**

![](_page_11_Figure_1.jpeg)

![](_page_11_Picture_2.jpeg)

![](_page_12_Figure_0.jpeg)

# I-V plot of C2 detector @ $\lambda$ =785 nm

![](_page_13_Figure_1.jpeg)

![](_page_13_Picture_2.jpeg)

# **Photocurrent Linearity**

![](_page_14_Figure_1.jpeg)

![](_page_14_Picture_2.jpeg)

#### Quantum Efficiency @ 25V

#### C2 detector

![](_page_15_Figure_2.jpeg)

![](_page_15_Picture_3.jpeg)

For each wavelength 20 measurements of photocurrent induced in the detector for various light intensities permit to estimate the mean value with combined errors of ratio between the number of drained charges and the number of incident photons.

![](_page_15_Picture_5.jpeg)

#### **Photocathode uniformity**

![](_page_16_Figure_1.jpeg)

![](_page_16_Picture_2.jpeg)

#### **Comparison between CNT growth at 500 and 700 °C**

![](_page_17_Picture_1.jpeg)

# 700 °C - D detector @ $\lambda$ =650 nm

![](_page_18_Figure_1.jpeg)

![](_page_18_Picture_2.jpeg)

## **Photocurrent Linearity**

![](_page_19_Figure_1.jpeg)

![](_page_19_Picture_2.jpeg)

![](_page_20_Figure_0.jpeg)

# Coating - Sample IBS0955 @ 500°

![](_page_21_Figure_1.jpeg)

Optical properties of TCO films and their electrical resistivity ensured the formation of near ideal ohmic contact. In order to obtain a CNTs coating, a thin film of a transparent conductive oxide (TCO), namely indium tin oxide (ITO) or zinc oxide (ZnO), is sputtered on the CNTs network so to partially cover the Au/Pt pads.

![](_page_21_Figure_4.jpeg)

![](_page_21_Picture_5.jpeg)

#### **Sample ITO photocurrent**

![](_page_22_Figure_1.jpeg)

![](_page_22_Picture_2.jpeg)

![](_page_23_Figure_0.jpeg)

![](_page_23_Picture_1.jpeg)

![](_page_24_Figure_0.jpeg)

The electric field applied uniformly over the entire CNT surface plays a fundamental rule making uniform the charge electrodes.

> The signal generated everywhere in the sample can be collected to the metallic electrodes through the ITO layer, whose resistivity is very low.

![](_page_24_Picture_3.jpeg)

# **Study of heterojunction Si-CNT**

![](_page_25_Picture_1.jpeg)

Contents lists available at ScienceDirect

Nuclear Instruments and Methods in Physics Research A NUCLEAR INSTRUMENTS & METHODS IN PHYSICS RESEARCH

journal homepage: www.elsevier.com/locate/nima

#### Electrical analysis of carbon nanostructures/silicon heterojunctions designed for radiation detection

A. Tinti<sup>a</sup>,<sup>\*</sup>, F. Righetti<sup>a</sup>, T. Ligonzo<sup>a</sup>, A. Valentini<sup>a</sup>, E. Nappi<sup>a</sup>, A. Ambrosio<sup>b</sup>, M. Ambrosio<sup>c</sup>, C. Aramo<sup>c</sup>, P. Maddalena<sup>b</sup>, P. Castrucci<sup>d</sup>, M. Scarselli<sup>d</sup>, M. De Crescenzi<sup>d</sup>, E. Fiandrini<sup>e</sup>, V. Grossi<sup>f</sup>, S. Santucci<sup>f</sup>, M. Passacantando<sup>f</sup>

<sup>a</sup> INFN, Sezione di Bari, Via Amendola 173, 70126 Bari, Italy

<sup>b</sup> CNR-SPIN U.O.S. di Napoli e Dipartimento di Scienze Fisiche, Universitá degli Studi di Napoli Federico II, Via Cintia 2, 80126 Napoli, Italy

<sup>c</sup> INFN, Sezione di Napoli, Via Cintia 2, 80125 Napoli, Italy

<sup>a</sup> Dipartimento di Fisica, Università degli Studi di Roma Tor Vergata, Via della Ricerca Scientifica 1, 00133 Roma, Italy

e INFN, Sezione di Perugia e Dipartimento di Fisica, Università degli Studi di Perugia, Piazza Università 1, 06100 Perugia, Italy

<sup>f</sup> Dipartimento di Fisica, Università degli Studi dell'Aquila, Via Vetoio 10, 67100 Coppito, L'Aquila, Italy

#### Nuclear Instruments and Methods in Physics Research A 629 (2011), 377-381

Keywords: Carbon nanotuber

#### ABSTRACT

A new class of radiation detectors based on carbon nanostructures as the active photosensitive element has been recently developed. In this scenario the optimization of the device, both in dark and on light irradiation, is a crucial point. Here, we report on electrical measurements performed in dark conditions on carbon nanofibers and nanotubes deposited on silicon substrates. Our experimental results were interpreted in terms of a multistep tunneling process occurring at the carbon nanostructures/silicon interface.

© 2010 Elsevier B.V. All rights reserved.

![](_page_25_Picture_19.jpeg)

![](_page_26_Figure_0.jpeg)

Depletion regions depend on applied voltage. The silicon bulk, 500  $\mu$ m thick, can be considered as a passive resistance except in the deplection areas.

The MIS deplecion zone cannot be reached from optical radiation because of the presence of metal.

Instead the depletion area created by the heterojunction CNT-Si can be reached and activated by radiation due to the characteristics of nanotubes. A fraction is absorbed inside CNT and converted in hole-electron pairs or excitons. The other reached silicon and is converted inside.

The described device can be considered as a "phototransistor"

![](_page_26_Picture_5.jpeg)

## **Equivalent circuit**

![](_page_27_Figure_1.jpeg)

IL: photocurrent generated from incident radiation
C\_j: Junction capacity
R\_sh: Shunt resistance
Rs: Resistance
D1: CNT-Si heterojunction
D2: MIS tunnel junction

In order to simulate the device we used the *PSpice Model Editor* 

![](_page_27_Picture_4.jpeg)

LFF Workshop – Napoli – November 22-23, 2012

#### Comparison with simulation sample C2 – 500 °C

![](_page_28_Figure_1.jpeg)

![](_page_28_Picture_2.jpeg)

# Comparison with simulation sample D – 700 °C

Sample D - Wavelength 650nm

![](_page_29_Figure_2.jpeg)

![](_page_29_Figure_3.jpeg)

![](_page_29_Picture_4.jpeg)

## **Other advantage**

The new Si-CNT detector can offer another advantage: the possibility to pixel large area in a very cheap and easy way.

$$\frac{d^2 I}{d\Omega d\omega} = \frac{3\sigma_z}{4c\pi\sqrt{\pi}} P_0 \frac{1}{\gamma^4 \theta^4} \exp(\frac{-\omega^2 \theta^4 \sigma_z^2}{16c^2})$$

The angular intensity distribution depends from wavelength as power 2 whereas the dependence form angle as power 4: two order of magnitude higher!

This means that with pixelled detector it will be possible to apply the LABM with higher sensitivity.

![](_page_30_Picture_5.jpeg)

# Nano-pixelled photocathodes

MWCNTs can be grown on different kind of substrates according the desired geometry. Nanolithography process allows to obtain finely pixelled elements over large surfaces.

![](_page_31_Figure_2.jpeg)

Nano-pixelled photocathodes may be obtained by means of nanolithography in a very cheap and easy way!

![](_page_31_Picture_4.jpeg)

# Nanolithography and patternization

![](_page_32_Figure_1.jpeg)

![](_page_33_Picture_0.jpeg)

![](_page_33_Picture_1.jpeg)

![](_page_34_Picture_0.jpeg)

Analog chip MAGMA developed in Naples

![](_page_34_Figure_2.jpeg)

# A possibile layout for a beamstrahlung photodetector

![](_page_34_Picture_4.jpeg)

1 cm<sup>2</sup> photodetector 8 pixel Coating with ITO Analog readout for each pixel 16 readout channels for each unit Reconstruct the

Reconstruct the beam shape at each frequency

<u>Note</u>: pixel dimensions are arbitrary. They depend on the light intensity and cost for pixel analog readout.

As higher is the pixel numer as precise the reconstruction of beam shape.

![](_page_35_Figure_0.jpeg)

## Two insulae sample

λ **= 650 nm** 

![](_page_35_Picture_3.jpeg)

![](_page_35_Picture_4.jpeg)

## **Summary**

A novel photon detector made of Silicon and CNT has been realized .

The main characteristics of this detector are:

- Low threshold
- Low dark current
- •Large plateau region
- •High linearity
- •Stable at room temperature

Large area for large photocathodes

**Easy pixellization** 

**Sub-micrometer dimension of pixels** 

•Quantum efficiency depending from light wavelength and from CVD temperature

Coating of CNTs surface has bee obtained with a conductive layer of ITO. Detector aging is under investigation.

The possibility to use a detector with the described characteristics for the large angle beamstrahlung monitor permits to avoid different kind of photodetectors for different wavelength range and to improve two order of magnitude the sensitivity of the method.

![](_page_36_Picture_14.jpeg)

![](_page_37_Picture_0.jpeg)

LFF Workshop - Napoli - November, 22-23 2012

# Thank you for attention

![](_page_37_Picture_3.jpeg)

![](_page_37_Picture_5.jpeg)

![](_page_38_Picture_0.jpeg)

![](_page_39_Figure_0.jpeg)

![](_page_40_Figure_0.jpeg)

INFN Istituto Nazionale di Fisica Nucleare

LFF Workshop – Napoli – November 22-23, 2012

![](_page_41_Figure_0.jpeg)

A. Ambrosio et al: "A prototype of a Carbon Nanotube microstrip radiation detector", Nuclear Instruments and Methods in Physics Research A 589 (2008) 398–403

![](_page_41_Picture_2.jpeg)

![](_page_41_Picture_5.jpeg)

#### Fotocurrent vs $\lambda$

![](_page_42_Figure_1.jpeg)

![](_page_42_Picture_2.jpeg)

Photocurrent normalized to the number of photons I<sub>nor</sub> vs photon energy, obtained illuminating the whole surface of a MWCNT sample with filtered light (■ ) as well as small part of the surface with laser

spots (\*). Continuous line indicates the absorbance spectrum of the same MWCNT sample

M. Passacantando et al: "Photoconductivity in defective carbon nanotube sheets under ultraviolet-visible-near infrared radiation", APPLIED PHYSICS LETTERS 93, 051911 2008

![](_page_42_Picture_6.jpeg)

![](_page_43_Figure_0.jpeg)

![](_page_43_Figure_1.jpeg)

![](_page_43_Picture_2.jpeg)

![](_page_43_Picture_3.jpeg)

#### **Photocurrent**

![](_page_43_Picture_5.jpeg)

![](_page_44_Figure_0.jpeg)

![](_page_44_Picture_1.jpeg)

![](_page_45_Figure_0.jpeg)